

### Declaration under 37 CFR 1.132

Ms. Chiou-Mei Chen, the declarant hereby states the following:

1. that she has a Master degree in the field of Environmental Engineering
2. that she is employed by the assignee in the above application, i.e. Industrial Technology Research Institute, as a research engineer;
3. that the following experiments were conducted by her alone or her and her associates together:

Experiment conditions:

Group I: wafers were 2cm above the ozone water;

Group II: wafers were partially immersed in the ozone water with an immersion depth of 4cm;

Group III: wafers were completely immersed in the ozone water having a depth of 20 cm;

- Photoreist: system 827 for the packing process
- Ozone concentration: 14~15% (w/w)
- Stripping temperature: room temperature and 50°C
- Rotation speed of the wafers: 3 rpm
- Stripping time: 3 minutes

Results:

**Table 1: stripping temperature at room temperature**

	Group I	Group II	Group III
Ozone concentration (%)	14.11	14.45	14.48
Thickness of photoresist (Å) before stripping	34740.6	34856.2	34666.1
Thickness of photoresist (Å) after stripping	32433.8	25199.3	34328.8
Stripping rate (Å/min)	768.9	3219.0	112.4

**Table 2: stripping temperature at 50° C**

	Group I	Group II	Group III
Ozone concentration (%)	14.26	14.61	14.73
Thickness of photoresist (Å) before stripping	34850.6	34923.2	34879.2
Thickness of photoresist (Å) after stripping	32350.7	20019.8	34457.2
Stripping rate (Å /min)	833.3	4967.8	140.7

4. that the method claimed in the above application has a surprising improvement in stripping rate in comparison with the methods disclosed in US2002/0011257A1 and US 6696228B2 cited in the Examiner' Office Action in the above application in view of the experiment results shown above.

That all statements made herein of her own knowledge are true and that all statements made on information and belief are believed to be true and further that these statements are made with knowledge that willful false statements and the like so made are punishable by fine or imprisonment, or both, under Section 1001 of title 18 of the United States Code and that such willful false statements may jeopardize the validity of the application or any patent issuing thereon.

Chiou-Mei Chen

Chiou-Mei Chen

Title: Research Engineer

Date: March 20, 2006